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PATENT
Attorney Docket No.: SAM-0256
Customer No.: 29344

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Sung-Un Kwean, et al.
Serial No.: 09/993,832
Filing Date: November 6, 2001
Title: ETCHING GAS COMPOSITION OF SILICON OXIDE AND METHOD OF
ETCHING SILICON OXIDE USING THE SAME

Examiner: Umez Eronini, Lynette T.
Group Art Unit: 1765

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

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Date

Vanessa Marakas
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TRANSMITTAL LETTER

Sir:

Enclosed herewith for filing in the above-identified patent application please find the following listed items:

1. Response to Final Office Action mailed on September 22, 2004; and
2. Return Postcard

In connection with the foregoing matter, please charge any additional fees which may be due, or credit any overpayment, to Deposit Account Number 50-1798. A duplicate copy of this letter is provided for this purpose.

Respectfully submitted,

David Silverstein
David Silverstein
Registration Number 26,336
Attorney for Applicant

Date: Nov 17, 2004
Mills & Ouello LLP
Eleven Beacon Street, Suite 605
Boston, MA 02108
Telephone: (617) 994-4900
Facsimile: (617) 742-7774
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